

Supplementary Information for

Parallel 3D laser microfabrication using axial focal spot shift tailored by laser beam divergence angle

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Table 3. Comparison of our technique and the other existing methods used to shift the focal spot in terms of the working principle, advantages, and drawbacks of each approach.

Method	Working principle	Axial shift	Advantages	Shortcomings
Divergence Focus Control (DFC) *	divergence modification based on Beam Expander approach	900 μm	- reduced cost - compact system design - high power applications - long term stability - no calibration required	- low speed - induce optical aberration at high magnifications - limited control of the wavefront
Diffraction Optical Element (DOE)-(Alvarez lens, Alvarez-Lohmann) Moiré diffractive optical elements	i) shifting two complementary cubic phase plates in opposite direction	86 μm ⁴⁹ 114 μm ²² 140 μm ⁴¹	- compact systems with large field of view and aperture⁵⁰ - high efficiency tuning⁵¹ - ultra-fast focal tuning with galvo-mirror angular scanning⁵²	- wavelength dependence⁵³ - sensitive to alignment and positioning⁵⁴ - high optical complexity required to correct beam walk-off - the resolution limit to low numerical apertures⁵²
Deformable mirrors (DM)	actuators deform the mirror surface when voltages are applied	53 μm ⁴² 85 μm ⁴³ 100 μm ⁴⁴ 120 μm ⁵⁵ 240 μm ⁴⁵	- can operate at kHz rates - wave front real-time correction⁵⁶ - closed-loop adaptive control	- actuator crosstalk- one actuator affects neighboring actuators - coating dependent - calibration required - the phase modulation that DM can reproduce is limited compared to SLM⁵⁶ - hysteresis movement⁴⁴
Electrically tunable lens (ETL)	electrically controlling the curvature of a flexible membrane filled with liquid	350 μm ⁴⁶	- high-speed (up to 1 kHz) - few ms response time⁴⁶ - compact design⁴⁶	- some lenses show hysteresis, affecting repeatability⁵⁷
Spatial light modulators (SLM)/ Adaptive optics (AO)	liquid crystal layer controlled by electric field	100 μm ⁵⁸ 160 μm ²¹ 400 μm ²¹ 500 μm ⁴⁷ 300 μm ⁵⁹ 800 μm ²¹	- high resolution - dynamic phase modulation⁶⁰ - high-speed refresh rates (ms)⁶¹ - generate multiple focal spots simultaneously⁶²	- high cost - increased system complexity - residual signal²¹ - resolution degradation without AO correction²¹ - temperature-induced drift in local phase shifts⁶³ - pixel cross-talk limiting the phase gradient⁶⁴ - pixelation leading to pulse replicas⁶⁵
Tunable Acoustic Gradient lens (TAG)	acoustic waves induce refractive index oscillations of an optical fluid	4 μm ⁶⁶ 23.5 μm ²⁵ 120 μm ⁶⁷ 135 μm ⁶⁸ 600 μm ⁴⁸	- compact system design - MHz-scale modulation, - fast depth scanning⁵⁶ - no step artifacts - pixelation-free²⁴	- continuous scanning focal position (cannot hold a fixed focal plane)²⁵ - limited lateral shaping capability⁵⁶ - lower resolution and degree of optical control than SLM²⁴